WELLS ST JOHN PS

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No	10/749 659
Filing Date	December 30, 2003
Inventor	
Assignee	Micron Technology Inc
Group Art Unit	2812
Examiner	Jennifer M. Kennedy
Attorney Docket No	MI22-2477
Customer No.	021587
Title Silicon-on-Inst	lator Comprising Integrated Circuitry

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

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- 1. Certificate of Facsimile Transmission
- 2. Transmittal Form
- 3. Statement of the Substance of the Interview

Dated: 10/21/04	By: Tat Valma	
	Pat Palmer	
	Telephone No. (509) 624-4276	6
	Facsimile No. (509) 838-342	4

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NUMBER OF PAGES IN FACSIMILE: ____5

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Certified Documer Reply to Incomple	Landscape Table on CD Propriety Remarks				
	SIGNA	TURE OF	APPLICANT, ATT	ORNEY.	OR AGENT
Firm Name	Wells St. John P.S.				,
Signature Signature					
Printed name Mark S. Matkin					
Date	10/21/04 Reg. No. 32,268				
CERTIFICATE OF TRANSMISSION/MAILING					
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Date

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P.03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No	
Filing Date	December 30, 2003
Inventor	Zhongze Wang
Assignee	Micron Technology, Inc.
Group Art Unit	2812
Examiner	Jennifer M. Kennedy
Attorney's Docket No	MI22-2477
Customer No	
Title	Silicon-on-Insulator Comprising Integrated Circuitry

STATEMENT OF THE SUBSTANCE OF THE INTERVIEW

To:

Commissioner for Patents

ATTENTION: Examiner Jennifer M. Kennedy

Group Art Unit 2812

P. O. Box 1450

Alexandria, VA 22313-1450

VIA FACSIMILE

From:

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An interview was conducted between the undersigned and Examiner Kennedy on October 18, 2004.

It was agreed during the interview that claims 11 and 62 as presented below would be allowable (subject to further searching), and that such amendments would be made/entered by the Examiner by an "Examiner's Amendment".

- Silicon-on-insulator comprising integrated circuitry, 11. comprising:
- substrate comprising а semiconductive silicon comprising layer of silicon-on-insulator circuitry, the silicon comprising layer comprising a pair of source/drain regions formed therein and a channel region formed therein which is received intermediate the source/drain regions;

a transistor gate received operably proximate the channel region; and

an insulator layer of the silicon-on-insulator circuitry received on the silicon comprising layer, the insulator layer comprising a first silicon dioxide comprising region in contact with the silicon comprising layer and running along enly a pertien at least a portion of the channel region between the source/drain regions, a silicon nitride comprising region in contact with the first sillcon dioxide comprising region and running along at least-a portion only a portion of the channel region, and a second silicon dioxide comprising region in contact with the silicon nitride comprising region, the silicon nitride comprising region being received intermediate the first and second silicon dioxide comprising regions.

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62. Silicon-on-insulator comprising integrated circuitry, comprising:

a substrate comprising a semiconductive silicon comprising layer of silicon-on-insulator circuitry, the silicon comprising layer comprising a pair of source/drain regions formed therein and a channel region formed therein which is received intermediate the source/drain regions;

a transistor gate received operably proximate the channel region; and

an Insulator layer of the silicon-on-insulator circultry received on the silicon comprising layer, the insulator layer comprising a first silicon dioxide comprising region in contact with the silicon comprising layer and running along enly—a portion at least a portion of the channel region between the source/drain regions, a silicon oxynitride comprising region in contact with the first silicon dioxide comprising region and running along at least a portion only a portion of the channel region, and a second silicon dioxide comprising region in contact with the silicon oxynitride comprising region, the silicon oxynitride comprising region, the silicon oxynitride comprising region being received intermediate the first and second silicon dioxide comprising regions.

Respectfully submitted,

Datad:

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Mark S. Matkin, Reg. No. 38,268